

# Inert Gas Purge Solutions

As semiconductor technology advances, new requirements have evolved with regards to the wafer storage environment throughout the production process.

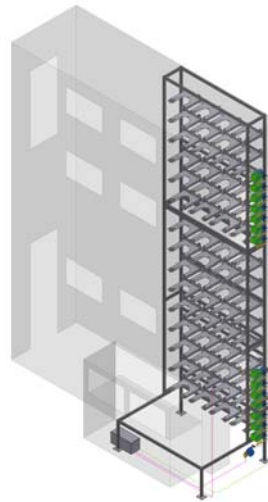
N<sub>2</sub> Purging protects wafers from the harmful effects of oxygen, water vapor and gaseous contaminants. The high purity purging systems are designed to meet SEMI standards and are available as "Standalone" units or "Fully Integrated" into Stockers with full communication with AMHS and OHV systems.

## FOUP Stocker Purge Solutions

Palbam Class / RICOR have developed solutions for all models of purgable FOUP's and SMIF's on the market.



SMART SHELF TECHNOLOGY



## FOUP Purge Station - Mk 1

The 300mm FOUP Purge Station - Mark 1, has been tested at Entegris Labs, and offers ultraclean purging of the Entegris F300 FOUP pod with dual purge ports.

Ideal for Research & Development Depts or for individual process stations requiring purge. Models for purging Dainichi and Shin Etsu FOUP 's also available.



Product	LxWxH (mm)	LxWxH (inch)	Cat. No.
FOUP Purge Station Mk 1	550x517x369		PCSE0501

## FOUP Purge Station - Mk 2

The newly designed 300mm Wafer FOUP Purge Station-Mark 2, is the ideal standalone unit for purging FOUPs with ultraclean Nitrogen.

OHV / AGV / PGV Compatible

Compatible with SEMI Specs:

E84, E57, E64, E15

Placement & Presence sensors

Programmable Purge Programs

Purge Flow monitoring

Compatible with all purgable FOUPs.

The increasing requirement for inert storage of wafers between process steps, makes this Purge Station an invaluable tool that Semiconductor Fabs simply can't afford to be without.



Product	LxWxH (mm)	LxWxH (inch)	Cat. No.
FOUP Purge Station - Mk2			PCSE0512



SMART SHELF TECHNOLOGY

## SMIF Purge Stations

Unique patented designs for purging both the Entegris E200 & the Asyst A200 Purgable SMIF Pods.



Product	LxWxH (mm)	LxWxH (inch)	Cat. No.
SMIF Purge Station - 2xE200 SMIF			PC-2-SMIF-E200
SMIF Purge Station - 2xA200 SMIF			PC-2-SMIF-A200